

CLAIMS

1. An exposure method in which a mask pattern is exposed onto a photosensitive substrate by an exposure body section, wherein
if an error occurs in an air-conditioning system that air-conditions an interior of a chamber in which the exposure body section is housed or occurs in a temperature control system that controls a temperature of the exposure body section, a power supply of a control system that controls the exposure body section is shut down.
2. An exposure method according to claim 1, wherein the power supply is shut down after a predetermined length of time has passed since the error occurred in the air-conditioning system or the temperature control system.
3. An exposure method according to claim 2, wherein the predetermined length of time includes a length of time to allow an operation of the exposure body section to be stopped.
4. An exposure method according to claim 2, wherein, when an error has occurred in the air-conditioning system or the temperature control system, the predetermined length of time includes a waiting time in which a command regarding the error is awaited after the error has been announced.
5. An exposure method according to claim 4, wherein the power supply is forcibly shut down after the waiting time has passed.
6. An exposure method according to claim 1, wherein, before the power supply is shut down, an operating state of the exposure body section at the time the error occurred in the air-conditioning system or the temperature control system is stored.
7. An exposure method according to claim 1, wherein the power supply of the air-conditioning system or the temperature control system is shut down after the power supply of the control system has been shut down.
8. An exposure method in which a substrate is exposed using illumination light irradiated via a mask by an exposure body section of which at least a portion is housed within a chamber, wherein

a power supply of a second control system that controls operations of the exposure body section is shut down prior to a power supply of a first control system that controls an environment within the chamber being shut down.

9. An exposure apparatus comprising:

an exposure body section that exposes a mask pattern onto a photosensitive substrate; and

a control system that controls operations of the exposure body section, wherein there is provided at least one of an air-conditioning system that conditions air in a chamber in which the exposure body section is housed, and a temperature control system that controls a temperature of the exposure body section,

and there is provided a power supply shutdown system that shuts down a power supply of the control system when an error occurs in the air-conditioning system or temperature control system.

10. An exposure apparatus according to claim 9, wherein the power supply shutdown system shuts down a main power supply of the entire exposure apparatus.

11. An exposure apparatus according to claim 9, wherein the power supply shutdown system has a timer that allows a predetermined time to pass from when an error occurs in the air-conditioning system or temperature control system until the power supply is shut down.

12. An exposure apparatus according to claim 11, wherein the timer includes a first timer that allows a time required to stop an operation of the exposure body section to pass.

13. An exposure apparatus according to claim 11, wherein the power supply shutdown system has an announcing device that, when an error occurs in the air-conditioning system or temperature control system, announces the error, and the timer includes a second timer that allows a waiting time to pass in which, after the error has been announced, a command regarding the error is awaited.

14. An exposure apparatus according to claim 13, wherein the timer includes a third timer that forcibly shuts down the power supply after the waiting time of the second timer has passed.

15. An exposure apparatus according to claim 9, wherein there is provided a storage apparatus that stores an operating state of the exposure body section at the time the error occurred in the air-conditioning system or the temperature control system.

16. An exposure apparatus according to claim 9, wherein the power supply shutdown system shuts down the power supply of the air-conditioning system or the temperature control system after the power supply of the control system has been shut down.

17. An exposure apparatus that exposes a substrate using illumination light irradiated via a mask by an exposure body section of which at least a portion is housed within a chamber, wherein

the exposure apparatus comprises:

a first control system that controls an environment within the chamber;

a second control system that controls an operation of the exposure body section;

and

a power supply shutdown system that shuts down a power supply of the second control system prior to shutting down a power supply of the first control system.

18. An exposure apparatus according to claim 17, wherein the first control system includes a gas supply system that supplies gas to at least a portion of the chamber, and a control system that controls supply conditions of the gas.

19. A device manufacturing method that includes a step in which, using the exposure apparatus according to claims 9 or 17, a device pattern is transferred onto a photosensitive layer formed on an object.